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 - L1: (6) substrate and bond near layer and encasing near layer
 - L2: (42) substrate and bond near layer and anodic near bond\$3
 - L3: (327) substrate and (bond near layer bonding near layer) and anodic near bond\$3
 - L4: (163) substrate and (bond adj layer bonding adj layer) and anodic near bond\$3
 - L5: (1712) substrate and (bond adj layer bonding adj layer metal) and anodic near bond\$3
 - L6: (163) substrate and (bond adj layer bonding adj layer) and anodic near bond\$3
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Highlight all hit terms initially

substrate and (bond adj layer bonding adj layer) and anodic near bond\$3

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	U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20050170546 A1	20050804	28	Method for making a micromechanical device by using a sacrificial substrate	438/48	438/68	
2	<input type="checkbox"/>	<input type="checkbox"/>	US 20050167752 A1	20050804	12	Electronic apparatuses, silicon-on-insulator integrated circuits, and fabrication methods	257/347	438/149	
3	<input type="checkbox"/>	<input type="checkbox"/>	US 20050146046 A1	20050707	13	Method for making probes for atomic force microscopy	257/773	438/14; 438/460	
4	<input type="checkbox"/>	<input type="checkbox"/>	US 20050139996 A1	20050630	18	Apparatus and method integrating an electro-osmotic pump and microchannel assembly into a die package	257/712	257/698; 257/714; 257/784	
5	<input type="checkbox"/>	<input type="checkbox"/>	US 20050132750 A1	20050623	13	Method for joining at least a first member and a second member, lithographic apparatus and device manufacturing method, as well as a device manufacturing method for the fabrication and testing thereof	65/40	101/463.1; 378/34	
6	<input type="checkbox"/>	<input type="checkbox"/>	US 20050111797 A1	20050526	48	Device package and methods for the fabrication and testing thereof	385/93		
7	<input type="checkbox"/>	<input type="checkbox"/>	US 20050110157 A1	20050526	48	Device package and method for the fabrication and testing thereof	257/776	257/712; 257/98; 257/99	
8	<input type="checkbox"/>	<input type="checkbox"/>	US 20050077633 A1	20050414	15	Anodic bonding structure, fabricating method thereof, and method of manufacturing optical scanner using the same	257/782	438/455	
9	<input type="checkbox"/>	<input type="checkbox"/>	US 20050063071 A1	20050324	19	Methods to make diffractive optical elements	359/742		
10	<input type="checkbox"/>	<input type="checkbox"/>	US 20050062163 A1	20050324	12	Electronic apparatus, silicon-on-insulator integrated circuits, and fabrication methods	257/758		
11	<input type="checkbox"/>	<input type="checkbox"/>	US 20050045973 A1	20050303	8	Micromechanical cap structure and a corresponding production method	257/414		